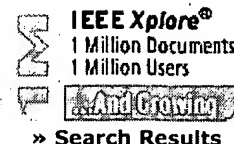


	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
1	BRS	L1	881	inductance same coil same temperature	USPA T	2004/09/2 7 07:34	

**IEEE Xplore®**  
RELEASE 1.8Welcome  
United States Patent and Trademark Office[Help](#) [FAQ](#) [Terms](#) [IEEE Peer Review](#)[Quick Links](#)

## Welcome to IEEE Xplore®

- ☐ Home
- ☐ What Can I Access?
- ☐ Log-out

## Tables of Contents

- ☐ Journals & Magazines
- ☐ Conference Proceedings
- ☐ Standards

## Search

- ☐ By Author
- ☐ Basic
- ☐ Advanced

## Member Services

- ☐ Join IEEE
- ☐ Establish IEEE Web Account
- ☐ Access the IEEE Member Digital Library

## IEEE Enterprise

- ☐ Access the IEEE Enterprise File Cabinet

Print Format

Your search matched **13** of **1074479** documents.  
A maximum of **500** results are displayed, **15** to a page, sorted by **Relevance** in **Descending** order.

**Refine This Search:**

You may refine your search by editing the current search expression or entering a new one in the text box.

☐ Check to search within this result set**Results Key:**

**JNL** = Journal or Magazine   **CNF** = Conference   **STD** = Standard

**1 Thin film high temperature superconductor RF coil and cryogenic preamplifier for low field MRI**

*van Heteren, J.G.; Fenzi, N.; James, T.W.; Bourne, L.C.;*

Nuclear Science Symposium and Medical Imaging Conference, 1993., 1993 IEEE Conference Record. , 31 Oct.-6 Nov. 1993

Pages:1708 - 1712 vol.3

[\[Abstract\]](#)   [\[PDF Full-Text \(328 KB\)\]](#)   IEEE CNF

**2 Axially-resolved study of highly ionized magnetron sputtering**

*Dickson, M.; Qian, F.; Hopwood, J.;*

Plasma Science, 1996. IEEE Conference Record - Abstracts., 1996 IEEE International Conference on , 3-5 June 1996

Pages:184

[\[Abstract\]](#)   [\[PDF Full-Text \(112 KB\)\]](#)   IEEE CNF

**3 The characteristics of magnetically enhanced large area processing plasmas**

*Cho, B.U.; Park, S.E.; Lee, J.K.; Lee, Y.J.; Yeom, G.Y.;*

Plasma Science, 2003. ICOPS 2003. IEEE Conference Record - Abstracts. The 30th International Conference on , 2-5 June 2003

Pages:161

[\[Abstract\]](#)   [\[PDF Full-Text \(174 KB\)\]](#)   IEEE CNF

**4 Modeling the inductively coupled plasma source and the comparison with experiments**

*Sheu, L.-R.; Hu, Y.; Lin, T.-L.; Tsai, S.-C.; Leou, K.-C.;*

Plasma Science, 1998. 25th Anniversary. IEEE Conference Record - Abstracts. 1998 IEEE International on , 1-4 June 1998

Pages:308

[\[Abstract\]](#)   [\[PDF Full-Text \(100 KB\)\]](#)   IEEE CNF